# Monthly LabAdviser update: 28/1 2019

|  |  |  |
| --- | --- | --- |
| Updated Subject | Contributor | Link to the updated pages |
| **PECVD3: low stress nitride**  Optimization of low stress nitride | **Thomas Pedersen @Nanolab** | [Deposition\_of\_Silicon\_Nitride\_using\_PECVD/PECVD3:\_Low\_stress\_nitride\_testing](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/Deposition_of_Silicon_Nitride/Deposition_of_Silicon_Nitride_using_PECVD/PECVD3:_Low_stress_nitride_testing) |
| **Temescal: Particle measurements**  Included a section on particles on films from Temescal. | **Rebecca B. Ettlinger @Nanolab** | [Thin\_film\_deposition/Temescal#Particulates\_on\_the\_films](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/Temescal#Particulates_on_the_films) |
| **Laser Micromachining:**  Have changed the values of the average output power with the new value after the laser came back from service in December | **Chantal Silvestre @Nanolab** | [Back-end\_processing/Laser\_Micromachining\_Tool](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Back-end_processing/Laser_Micromachining_Tool) |
| **Mask and pattern design**  New link to installation of Clewin 5 | **P. Jesper Handberg @Nanolab** | [Lithography/Pattern\_Design\_and\_Mask\_Fabrication/CleWin](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Lithography/Pattern_Design_and_Mask_Fabrication/CleWin) |
| **AFM Icon 2**  The new AFM Icon placed in the basement of 346 has been added to the AFM LabAdviser page. | **Berit Herstrøm @Nanolab** | [Characterization/AFM:\_Atomic\_Force\_Microscopy](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Characterization/AFM:_Atomic_Force_Microscopy) |

# Equipment Manuals updated in LabManager (since 16th of November):

As an approved user on a piece of equipment you have to make sure you have read and understood the latest version of the manual before using the equipment.

|  |  |
| --- | --- |
|  | **Manual for PL-mapper**, ver 2.3 |
|  | **Manual for Nikon ECLIPSE L200 (2) optical microscope**, ver 2.2 |
|  |
|  |
|  | **Manual for Nikon ECLIPSE L200 optical microscope**, ver 5.2 |
|  |
|  |
| http://d4.danchip.dtu.dk/D4Doc/res/menu/user_bullet.gif | **Manual for AFM Icon-PT 1 & 2**, ver 4 |
|  | **Manual for ALD 1**, ver 3.1 |
|  | **Manual for Electroplating-Ni (Technotrans microform.200)**, ver 7 |
|  |
|  |
|  | **Manual for Sputter Coater 03**, ver 2 |
|  |
|  |
|  | **Manual Cammax die bonder** , ver 1.3 |
|  | **Manual for Furnace: Multipurpose Annealing**, ver 2.4 |
| http://d4.danchip.dtu.dk/D4Doc/res/menu/user_bullet.gif | **Manual for HMDS\_Vapor Prime Oven Star2000**, ver 6 |
|  | **Manual for Developer-6" Bench**, ver 5 |
|  |
|  |
|  | **Manual for Developer TMAH Stepper.**, ver 3 |
|  |
|  |
|  | **Manual for Oven: HMDS-2**, ver 3 |
|  |
|  |
|  | **Manual for LPCVD Poly Silicon Furnace (6") (E2)**, ver 5 |
|  | **Manual for Temescal E-beam Evaporator**, ver 1.1 |
|  |
|  | **Manual for Aluminium etch**, ver 5 |
|  |
|  | **Manual for RCA clean**, ver 5 |